### IBE Gratings – Surface Clean Up Experiment

- Problem: IBE gratings had bat ears
- Experiment Goal: Develop process to eliminate bat ears

SEM pictures courtesy of Photodigm, Inc.

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### **Bat Ears**



Duty cycle ~ 36%, Grating Depth ~ 500 Å

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## IBE and Photo Resist Removal

IBE Run 08/15/04

- IBE Process
  - Using Epi-Grade GaAs with positive resist grating mask
  - Hard Bake 5 min. at 95°C
  - Flowing Ar, 300 V, Beam Current 50 mA
  - Etch time 2 min, 11 sec (Grating target depth 700 Angstroms)
- Positive Photo Resist Removal
  - O2 Ashed for 15 min at 125 W and 0.58 torr
  - Acetone/IPA/nitrogen dry
  - O2 Ashed for 10 min at 125 W and 0.58 torr
- After photo resist removal, I cleaved the piece into two pieces. (A and B)

### Surface Cleans

#### – Piece A was cleaned as follows:

- Acetone Boil 10 min at 150 degrees C
- Acetone/IPA/Nitrogen
- Ash 5 min
- BOE 1:10 for 30 sec
- Bake at 95 degree C for 3 min
- Wet etched H2S04:H202:H20 (1:8:160) for 10 sec

#### - Piece B was cleaned as follows:

- Scrubbed with q-tip in acetone bath ~ 5 min
- Acetone/IPA/Nitrogen
- Ash 5 min
- BOE 1:10 for 30 sec
- Bake at 95 degree C for 3 min
- Wet etched H2S04:H202:H20 (1:8:160) for 10 sec



9070-A1

9070-A3

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9070-B

9070-B2

### Results

- Acetone Boil looks better than Acetone Scrub
- Duty Cycle is ~ 16 32% (Target is 40 60%)
- Grating Depth is ~ 600 722 Å
- Bat Ears are gone
- Estimate that the wet etch clean up removed ~ 400 Å of GaAs

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## Second Experiment Run

- A different IBE process was run with higher beam current (123 mA) to reduce GaAs/Photo Resist selectivity to ~ 1:1
- Normaski inspection of witness etch piece showed increased surface roughness compared to lower beam current process
- Status: Pending SEM pictures of gratings

# Third IBE Experiment

- Problem: Low duty cycle
- Experiment Goal: Improve duty cycle to 40 60% target range while eliminating bat ears and achieving smooth surface
- Status
  - Selected two grating samples
    - One piece at diffraction efficiency peak (28.2%)
    - Another piece on low side of peak (16.06%)
  - IBE at Beam Current 50 mA for 2 min
  - Pending surface cleans
    - Plan to vary wet etch times

## Future Work

- Get Experiment 2 and 3 Results (Sep 8)
- Run Real Epi and submit for regrowth (Sep 10)
- Continue learning Grating Software